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Applicants
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U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
LV	A	5,534,462	07/09/1996	Fiordalice, et al.			

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FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
LV		EP 0 696 819 A1	14 Feb 1996	Europe				X
LV		WO 99/33102	01 Jul 1999	PCT				X

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	BORST, Et. al.; "Chemical Mechanical Polishing Mechanisms of Low Dielectric Constant Polymers in Copper Slurries"; Jour. Electrochem. Soc., 146;11;4309-4315 (1999)
	MATSUBARA, et al., "Low-k Fluorinated Amorphous Carbon Interlayer Technology for Quarter Micron Devices"; IEDM 96:369-372
	IBM Technical Disclosure Bulletin; "Lithographic Patters with a Barrier Liner"; Vol. 32; No. 10B; March 1990

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